

# MPI TS150 | 150 mm Manual Probe System

For accurate and reliable DC/CV and RF measurements

## Microscope Mount and Movement

- Stable bridge for high quality optics
- Linear Z lift for easy reconfiguration
- 25 x 25 mm air bearing or 50 x 50 mm linear XY movement

## Adjustable Platen Height

- Micrometer control for precise adjustment
- 20 mm range for various applications

## Probe Platen

- Stable and rigid design
- Supports DC/CV and RF measurements
- Rectangular adjustments for RF positioners
- Designed for maximum thermal stability

## RF Calibration

- 2 auxiliary chucks for calibration substrates
- Built-in ceramic for accurate calibration
- 1 µm flatness for consistent contact quality

## Unique Platen Lift

- Three discrete positions for contact, separation (300 µm) and safety loading (3 mm)
- Safety lock function at loading position
- ±1 µm repeatability for consistent contact quality

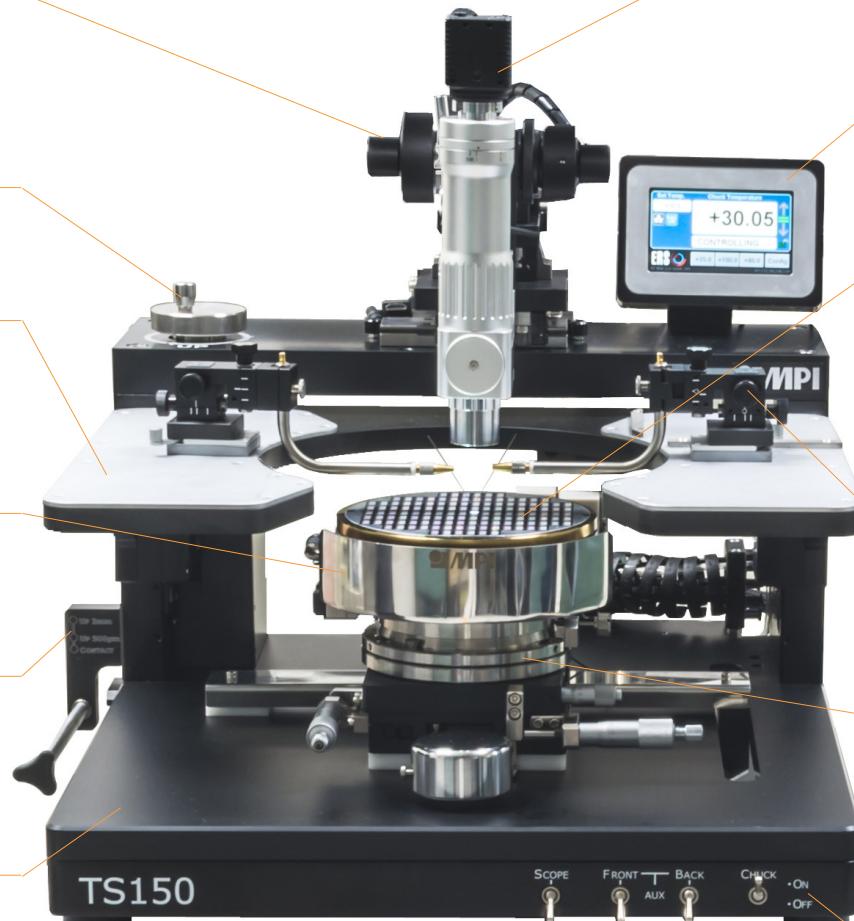
## Ultra Small Footprint

- Designed for bench top use
- Comes with vibration absorber base
- Low profile design for maximum usability
- Ideal for load pull applications

## \*\*\*Available Options\*\*\*

- Vibration isolation platform
- EMI-shielded DarkBox
- Vacuum pump and air compressor unit

- Table with integrated rack for thermal controller, computer and keyboard push tray
  - Dual monitor stand option & Instrument shelf option



## Microscope and Optics Options

- Various optics options available
- Stereo MPI ST45 or single tube MPI SZ10, MZ12 with up to 12x zoom and 95 mm working distance
- High Power microscopes FS70/PSM-1000
- HDMI cameras with up to 5 MP available

## Thermal Chuck Integration

- Seamless integration of the thermal controller touch screen panel provides most convenient operation

## Modular Chucks

- Various ambient or thermal chucks
- Choice of triaxial or coaxial connection
- Wide range of temperature up to 300 °C
- Field upgradable for reduced cost of ownership
- Easy switch between center and small wafer size control

## DC and RF Positioners

- Supports up to 4 RF and 8 DC positioners
- Wide range of positioners available
- Dedicated probe arms for coaxial, triaxial, Kelvin and RF measurements

## Chuck XY-Theta Stage Movement

- Unique puck controlled air bearing stage for quick single handed operation
- 175 x 225 mm XY movement
- Including 25 x 25 mm fine micrometer control
- Extra wide Y-range for easy loading
- ±5° Theta fine adjustment

## Front Mounted Vacuum Control

- Easy access
- Clearly marked